

What is claimed is;

1. A surface inspection method for inspecting a pattern formed at a surface of a test piece, comprising:

5 a first step in which a plurality of inspection conditions that are different from each other are set;

a second step in which light from the surface of the test piece is detected by irradiating illumination light onto the surface of the test piece under each of
10 said plurality of inspection conditions;

a third step in which a plurality of sets of detection information corresponding to said plurality of inspection conditions are generated based upon the detected light;

15 a fourth step in which a logical OR of said plurality of sets of detection information is obtained; and

a fifth step in which a decision is made as to whether or not said pattern at the surface of the test
20 piece is acceptable based upon results of the logical OR.

2. A surface inspection method according to claim 1, wherein in said third step:

25 an image of the surface is formed by condensing

at least one of specific diffracted light, scattered light and reflected light from the surface of the test piece under each of said plurality of different inspection conditions;

5 said image is converted to an image signal; and
 said detection information is generated based upon said image signal.

3. A surface inspection method according to claim 1,
10 wherein:

 said pattern comprises a plural types of cyclical pattern;

 said plurality of inspection conditions are respectively set in correspondence to pitches of said
15 plural types of cyclic pattern.

4. A surface inspection method according to claim 1,
 wherein:

 said plurality of inspection conditions are each
20 set by rotating the test piece around a specific axis of rotation to change an angle of incidence of said illumination light onto the test piece and a light-receiving angle of the light from the test piece.

25 5. A surface inspection method according to claim 1,

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wherein:

5 said plurality of inspection conditions are each set by setting at least one of an angle of incidence of said illumination light, a light-receiving angle of the light from the test piece, and a wavelength of said illumination light.

6. A surface inspection method according to claim 1, wherein:

10 said plurality of inspection conditions are each set in conformance to a order of diffracted light corresponding to a specific pitch of the pattern on the test piece.

15 7. A surface inspection method according to claim 1, wherein:

said plurality of inspection conditions are each set by adjusting a wavelength of said illumination light.

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8. A surface inspection method for inspecting a pattern formed at a surface of a test piece, comprising:

25 a first step in which a plurality of diffraction conditions that are different from each other are set;

generated in said sixth step is obtained; and

an eighth step in which a decision is made as to whether or not said pattern at the surface of the test piece is acceptable based upon results of the logical

5 OR.

9. A surface inspection apparatus that conducts an inspection of a pattern formed at a surface of a test piece, comprising:

10 a stage that holds the test piece;

an illumination device that irradiates illumination light onto the surface of the test piece;

a light-receiving device that detects at least one of diffracted light, scattered light and reflected
15 light from the test piece;

a drive device the makes it possible to vary at least one of; an angle of inclination of said stage, a position of said illumination device and a position of said light-receiving device, in order to guide the
20 light from the surface of the test piece to said light-receiving device under a plurality of different inspection conditions; and

an arithmetic operation device that sets said plurality of inspection conditions, generates a
25 plurality of sets of detection information in

correspondence to said plurality of inspection conditions based upon the light detected by said light-receiving device, obtains a logical OR of said plurality of sets of detection information thus
 5 generated and makes a decision as to whether or not said pattern at the surface of the test piece is acceptable based upon results of said logical OR.

10. A surface inspection apparatus that conducts an
 10 inspection of a pattern formed at a surface of a test piece, comprising:

a first illumination device that irradiates illumination light onto the surface of the test piece at a variable first angle of incidence;

15 a second illumination device that irradiates illumination light from a light source formed in a slit onto the surface of the test piece at a second angle of incidence larger than said first angle of incidence;

20 a light-receiving device that detects light originating from the surface of the test piece; and

an arithmetic operation device that generates first detection information based upon light originating from the surface of the test piece through
 25 irradiation by said first illumination device detected

by said light-receiving device, generates second
detection information based upon light originating
from the surface of the test piece through irradiation
by said second illumination device detected by said
5 light-receiving device, obtains a logical OR of said
first detection information and said second detection
information and makes a decision as to whether or not
said pattern at the surface of the test piece is
acceptable based upon results of said logical OR.

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11. A recording medium having recorded therein a
program employed in a surface inspection apparatus
that conducts an inspection of a pattern formed at a
surface of a test piece, said program comprising:

15 a first instruction for setting a plurality of
different inspection conditions;

a second instruction for detecting light
originating from the surface of the test piece by
irradiating illumination light onto the surface of the
20 test piece under each of said plurality of inspection
conditions;

a third instruction for generating a plurality of
sets of detection information corresponding to said
plurality of inspection conditions based upon the
25 detected light;

a fourth instruction for obtaining a logical OR
of said plurality of sets of detection information;
and

5 a fifth instruction for making a decision as to
whether or not said pattern at the surface of the test
piece is acceptable based upon results of said logical
OR.

12. A data signal embodied in a carrier wave
10 comprising a program employed in a surface inspection
apparatus that conducts an inspection of a pattern
formed at a surface of a test piece, said program
comprising:

a first instruction for setting a plurality of
15 different inspection conditions;

all
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a second instruction for detecting light
originating from the surface of the test piece by
irradiating illumination light onto the surface of the
test piece under each of said plurality of inspection
20 conditions;

a third instruction for generating a plurality of
sets of detection information corresponding to said
plurality of inspection conditions based upon the
detected light;

25 a fourth instruction for obtaining a logical OR

of said plurality of sets of detection information;
and

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5 a fifth instruction for making a decision as to
whether or not said pattern at the surface of the test
piece is acceptable based upon results of said logical
OR.

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